

# TOUCHSCREEN SERIES C

AWARD WINNING SOFTWARE MEETS ADVANCED HARDWARE

- TOUSIMIS HAS NOW INTEGRATED OUR AWARD WINNING TOUCHSCREEN SOFTWARE EXPERTISE INTO THE NEW SERIES C LINE

- THE TOUSIMIS 'SERIES C' LINE HAS LED THE WAY IN RELIABILITY, YIELD, AND SIMPLICITY FOR OVER 15 YEARS IN BOTH INDUSTRIAL AND RESEARCH FACILITIES WORLDWIDE



## TOUCHSCREEN RECIPES FOR DRYING 4", 6" AND 8" WAFERS

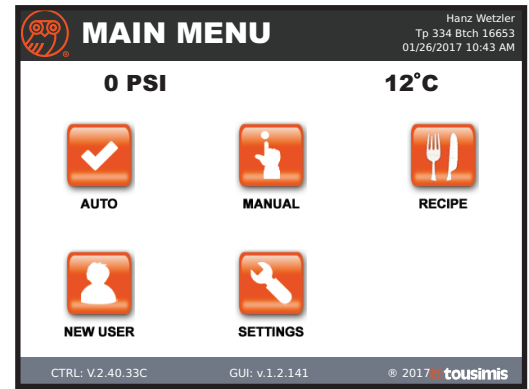
- PROGRAMMABLE TOUCHSCREEN CONTROL
- INTEGRATED INTERNAL SOTER CONDENSER
- 0.08  $\mu\text{M}$  INTERNAL LC02 FILTRATION PROTECTS CHAMBER PROCESS
- DEDICATED SLOW FILL CREATES IDEAL FLUID DYNAMICS FOR THE MOST SENSITIVE DEVICES
- NON-MECHANICAL CHAMBER FLUID STIRRING ELIMINATES THE NEED FOR PARTICLE GENERATING FRICTION DEVICES
- SUBSTRATE PROCESS FLEXIBILITY VIA MULTIPLE CHAMBER INSERTS AND WAFER HOLDERS FOR UP TO 8" WAFERS, PIECES AND DIE

MADE IN U.S.A.

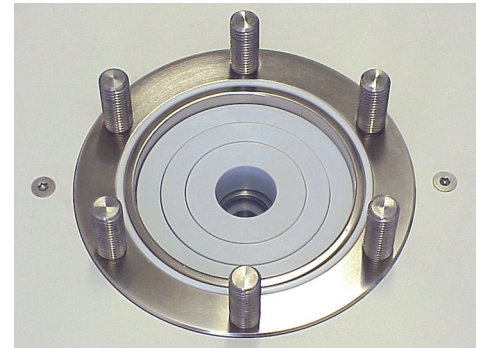
4" - Automegasamdri®-934, Series C  
 6" - Automegasamdri®-936, Series C  
 8" - Automegasamdri®-938, Series C

## FEATURES

- Bright LCD Touch Screen Control
- Use Factory Default Automatic Settings or Create Custom Recipes
- Optional "Stasis Software" (Patent Pending) for versatile sample types
- Process up to 5 wafers per process run with each system
- HF Compatible Wafer Holders and 10mm square holder included with each system
- Tousimis® HF compatible Wafer Holders\* may be used to etch and process your wafers minimizing handling
- Unique chamber inserts\* easily reduce chamber ID decreasing LCO<sub>2</sub> consumption
- High efficiency internal closed loop refrigeration integration\*
- "Vortex Swirl" non-mechanical purge stirring (Patent Pending) eliminates moving parts for easy maintenance
- Repeatable operating parameters insuring "reproducibility" of results
- Static pressure control module helps insure automatic safe pressure stability
- Internal filtration system delivers clean LCO<sub>2</sub> into process chamber down to 0.08µm
- New 'Slow Fill' Control for the most delicate Sample Types
- LCO<sub>2</sub> flow is controlled through Micro Metering Valves with Vernier handles for precise flow control and easy position setting readjustment
- Chamber illumination with view port facilitates chamber status visualization\*
- All internal surfaces are inert to CO<sub>2</sub>, Acetone and Ultrapure Alcohols
- Cleanroom static-free compatible design
- External mounted Post Purge Filter Assembly for EZ preventive maintenance maintenance\*
- The patented internal SOTER™ Condenser\* quietly captures and separates CO<sub>2</sub> exhaust and waste alcohols
- All electronic components meet CE, UL and/or U.S. Military Specifications



Touch Screen Main Menu



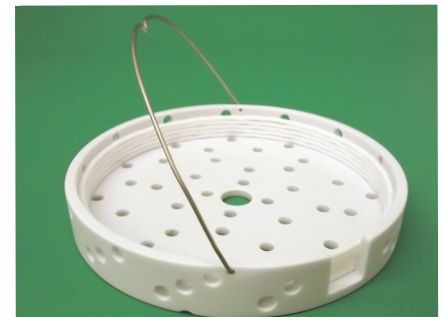
4" Process Chamber with Chamber Inserts

## SPECIFICATIONS

- Cabinet: 19.8" (50.3cm) Width x 31.7" (80.6cm) Depth x 44.5" (113.0cm) Height
- System Set-Up Area Footprint: 27" (68.6cm) Width x 38" (96.5cm) Depth x 44.5" (113cm) Height
- 120V or 220V / 50-60Hz systems available

## STANDARD ACCESSORIES

- LCO<sub>2</sub> High Pressure braided stainless steel inert Teflon® lined hose. 10ft (3m) long for clean room operation (Other lengths available upon request)
- Double T-Filter Assembly (Cat. #8785) pre-installed onto the LCO<sub>2</sub> supply High Pressure hose. Flows LCO<sub>2</sub> twice thru 0.5 µm filters with 99.5% particulate retention prior to LCO<sub>2</sub> entering Automegasamdri®
- Tool set included for connecting LCO<sub>2</sub> chamber supply line
- Static free exhaust tubing provided for all exhaust outlets
- Spare chamber O-ring (3), chamber lamps (2), and slo-blow fuses (2x3A and 2x8A)
- Chamber inserts\* enable chamber ID reduction down to 1.25" ID Chamber Size
- HF Compatible Wafer Holder Set included with each system
- 2 year warranty on all parts and labor
- Free lifetime technical support



HF Compatible Wafer Holder

\* Most Autosamdri® feature U.S. patents (# 6,493,964, #6,678,968) or patents pending

**Note:** Actual delivered model or accessories may vary slightly, as advancements are being constantly applied